# NOMINATING COMMITTEE
COMMUNITY COMMISSION FOR PUBLIC SAFETY AND ACCOUNTABILITY

**City of Chicago**
**NOTICE OF CCPSA NOMINATING COMMITTEE MEETING**

The Nominating Committee for the Community Commission for Public Safety and Accountability will hold a regular public meeting on the following date, time, and location:

**Saturday, November 7, 2026, 10:30 AM**
**DePaul College Prep,**
**3300 N. Campbell Ave, Chicago, IL 60618**

## AGENDA

I. Roll call & quorum determination
II. Approval of remote attendance
III. Approval of agenda
IV. Approval of past minutes
V. Public comment
VI. Closed meeting to interview candidates for vacancy on the CCPSA
VII. Closed meeting to deliberate on candidates for the vacancy on the CCPSA
VIII. Discussions and Votes
    1. Nominations for current Commission vacancy
    2. Draft recommendations to amend Commission composition requirements under the CCPSA Ordinance
IX. Additional announcements, and announcement of the next meeting
    1. December 5, 2026. Quarterly meeting of the District Councils. Location to be determined.

Please Note: Items on this agenda are subject to change. If you have any questions regarding this agenda, please contact the Community Commission for Public Safety and Accountability by emailing CommissionNomination@cityofchicago.org.

The Nominating Committee will provide an opportunity for public comment. Each person participating in public comment will have up to 2 minutes to speak. A total of 20 minutes will be dedicated to public comment. Anyone interested in speaking during the public comment period must write their name on a card provided at the meeting and give it to the members of the Nominating Committee or staff in the meeting room any time within 30 minutes of the start of the meeting. If the number of interested speakers exceeds the time dedicated to public comment, speakers will be

selected by a random drawing. Anyone may submit written public comment by delivering it at the public meeting or by emailing it to CommissionNomination@cityofchicago.org.